Fig.1

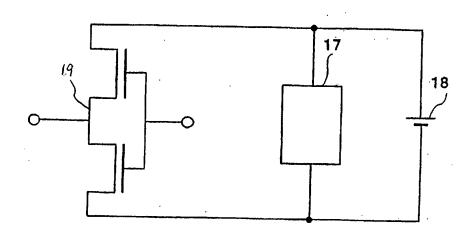
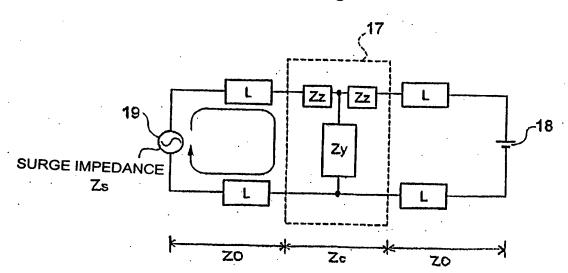
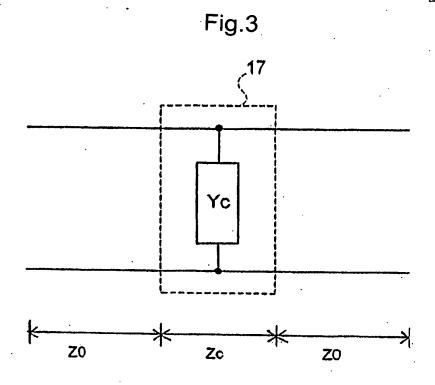
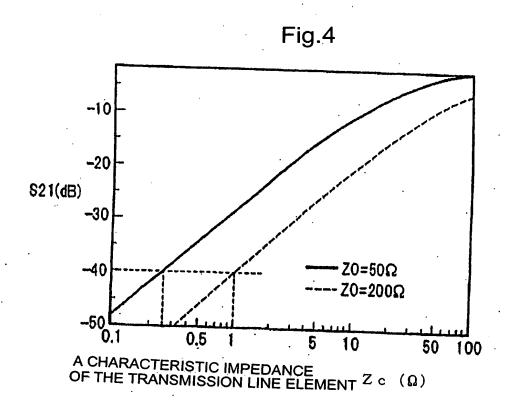


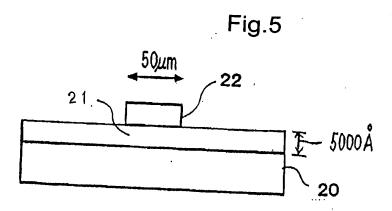
Fig.2







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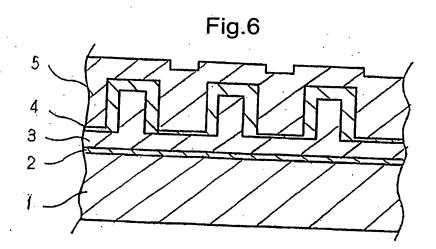


Fig.7

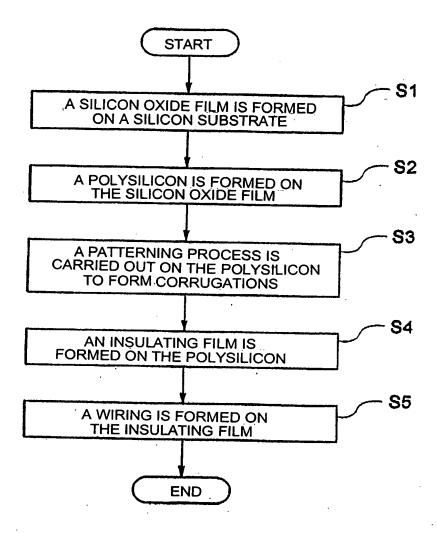


Fig.8

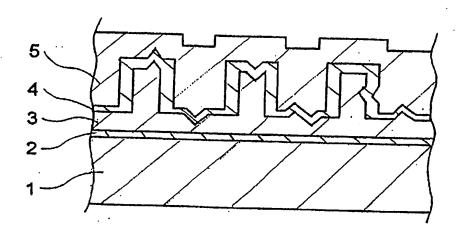


Fig.9

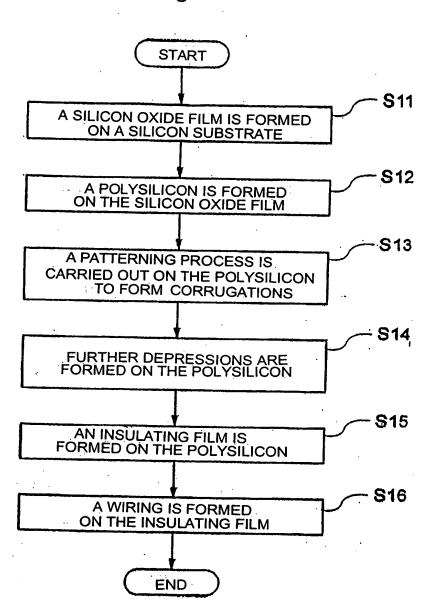


Fig.10

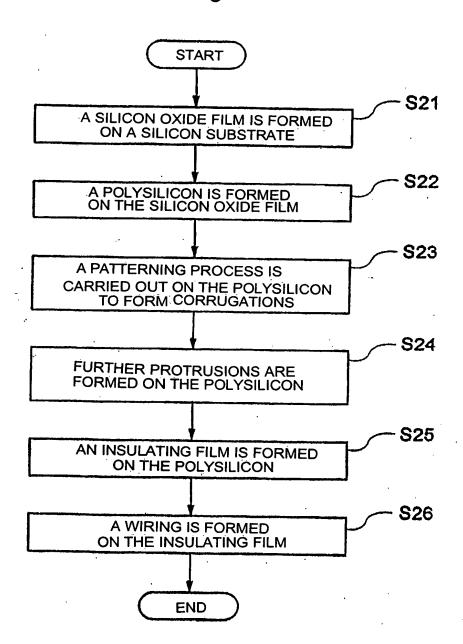


Fig.11

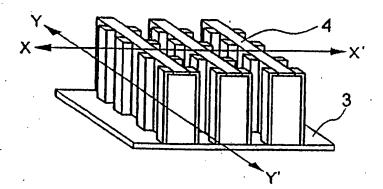
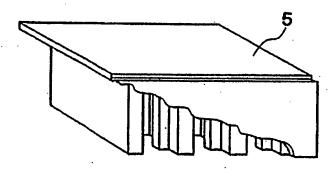


Fig.12



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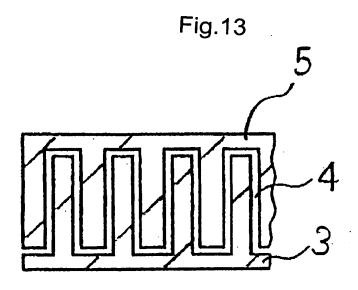


Fig.14

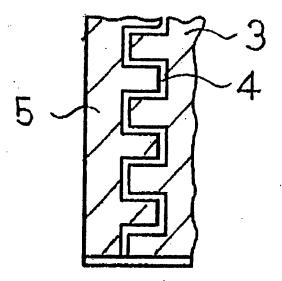
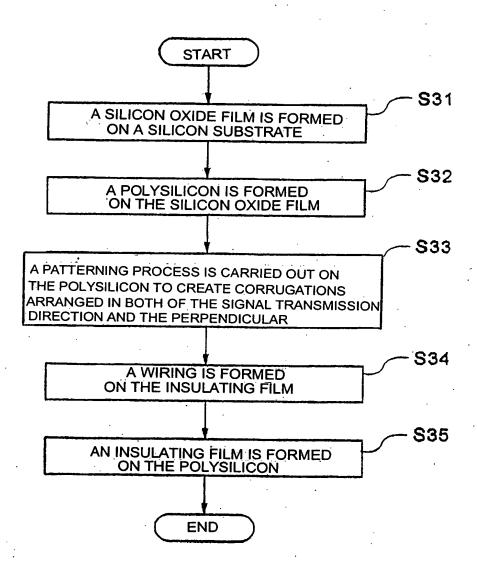
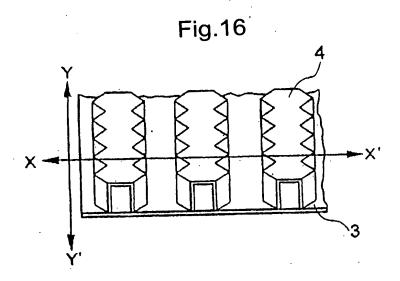
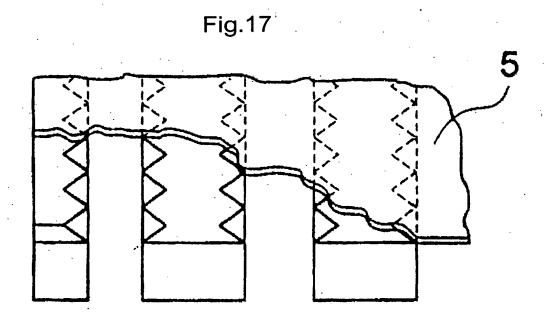


Fig.15

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Fig.18

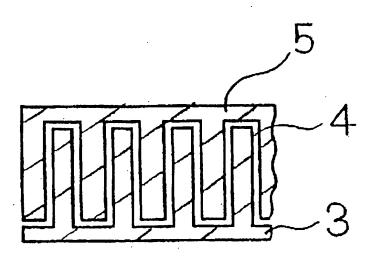


Fig.19

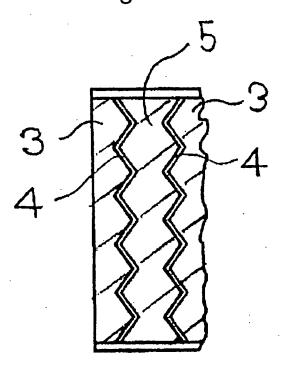


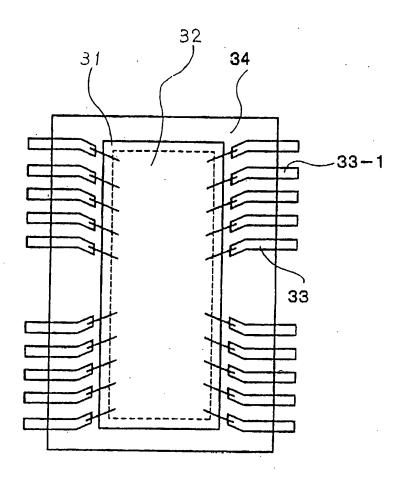
Fig.20 **START S41** A SILICON OXIDE FILM IS FORMED ON A SILICON SUBSTRATE **S42** A POLYSILICON IS FORMED ON THE SILICON OXIDE FILM **S43** A PATTERNING PROCESS IS CARRIED OUT ON THE POLYSILICON CORRUGATIONS ARRANGED IN THE DIRECTION PERPENDICULAR TO THE SIGNAL TRANSMISSION DIRECTION ARE CREATED, AND EACH CORRUGATION IS WORKED TO HAVE A PLURALITY OF RIDGES **S44** AN INSULATING FILM IS FORMED ON THE POLYSILICON **S45** A WIRING IS FORMED ON THE INSULATING FILM END

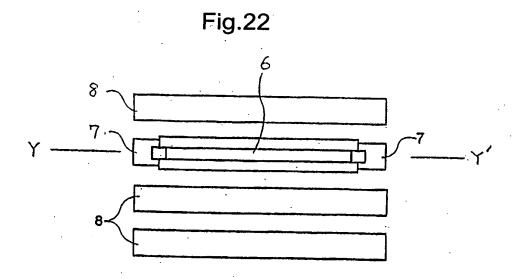
44.74 . 4. 7.74

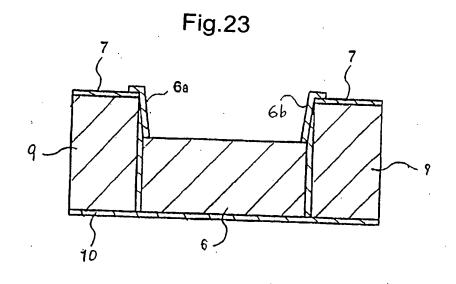
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Fig.21







START

START

START

SPOXY RESIN LAYERS ARE FORMED ON A GROUND SURFACE

A POWER SUPPLY LEAD ARE FORMED ON EPOXY RESIN LAYERS

A TRANSMISSION LINE ELEMENT IS FORMED IN THE SITE SANDWICHED BETWEEN EPOXY RESIN LAYERS

END

END

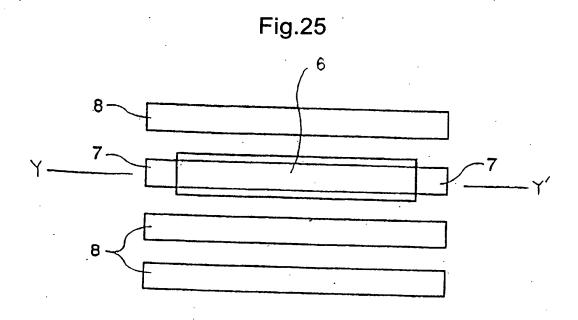


Fig.26

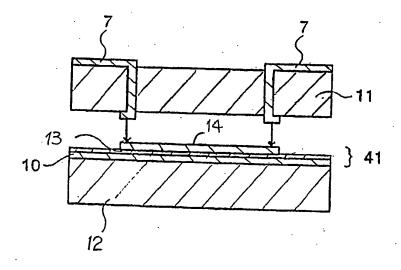


Fig.27

